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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Joachim H. Schober, Heimo Scheucher and Paul Hubmer

Title of Invention : SEMICONDUCTOR WAFER WITH PROCESS CONTROL MODULES

Date Filed : February 21, 2002

Serial No. : 10/081,893

Examiner : THAI, LUAN C

Art Unit : 2827

Attorney Docket No. : AT 010007

Box Non-fee Amendment
Commissioner for Patents
Washington, DC 20231

AMENDMENT

SIR:

This is responsive to the Office Action dated January 14, 2003, in connection with the above-referenced patent application.

Applicants have amended the application as follows:

IN THE SPECIFICATION:

Replace page 4, paragraph 2 (lines 3-6) as follows:

In English-language jargon such exposure fields are referred to as "reticles". In the present case, the semiconductor wafer 1 has two so-called drop-in areas 3, which in known manner serve for